

depositing a coating on the substrate over at least a portion of the ion beam milled surface thereof.

B1
amended
40. (New) The method of claim 39, wherein said ion beam milling is performed so as to reduce the thickness of substantially the entire substrate by from about 4-20 Å.

41. (New) The method of claim 39, wherein the ion beam milling is performed using an ion energy of from about 1500-2000 eV.

REMARKS

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This is a continuation of Serial No. 09/703,709. The original claims have been canceled, and new claims 39-41 have been added. It is respectfully requested that the application be amended as set forth above prior to initial examination thereof.

Respectfully submitted,

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